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second object table in a first direction substantially perpendicular to said surface of the substrate, and to create a height map thereof;

a position measuring system located at said exposure station for measuring a position of said physical reference surface in a first direction substantially perpendicular to said substrate surface, after movement of said second object table to said exposure station; and

a position controller constructed and arranged to control the position of said second object table in at least said first direction, during exposure of said target portion, in accordance with said height map and said position measured by said position measuring system.

See the attached Appendix for the changes made to effect the above claim.